

FIG. 1

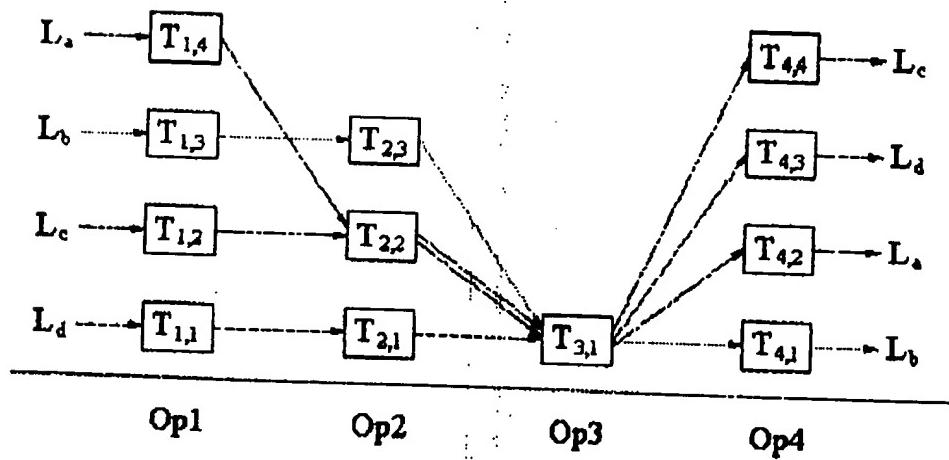


FIG. 2

Lot: L _a		Process Flow=PF101					D _a
Ld _a	operation	Op1	Op2	Op3	Op4	---	
Yd _a	tool	T _{1,1}	T _{2,2}	T _{3,1}	T _{4,2}	---	
wafer	W _{a,1}	W _{a,2}	W _{a,3}	W _{a,4}	---		
yield	Y _{a,1}	Y _{a,2}	Y _{a,3}	Y _{a,4}	---		

FIG. 3

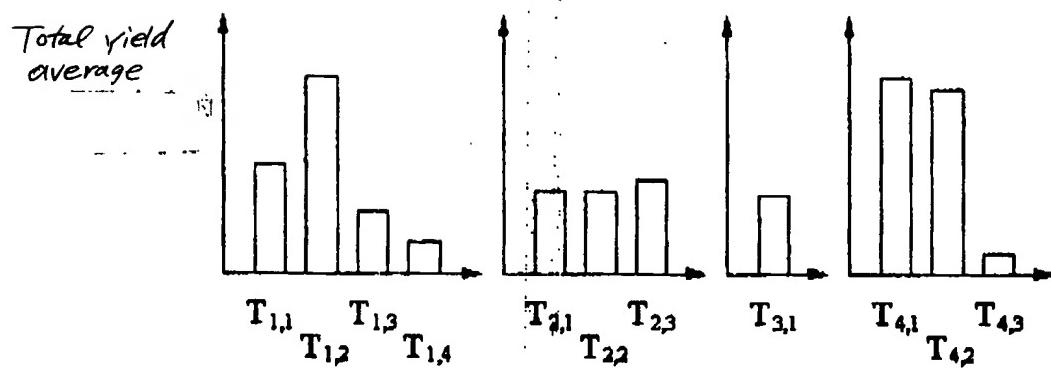


FIG. 4